

# Introduction



The metal-oxide-semiconductor field-effect transistor consists of two p-n junctions either side of a MOS diode which acts as the gate.

MOSFET devices make up around 90% of the electronics industry due to their low power and their small size (compared with bipolar transistors).

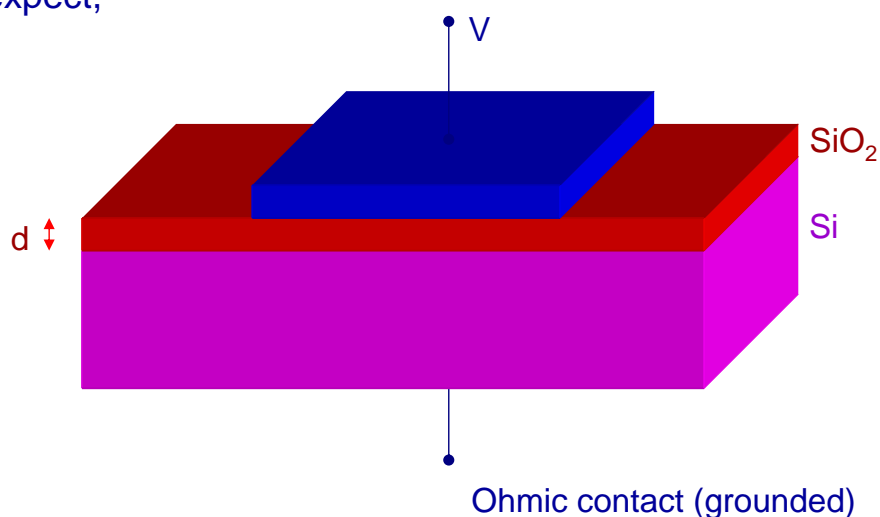
They are the basis for MOS memory structures such as Flash memory and CMOS logic structures.

Before we can understand the MOSFET we need to look closely at the MOS diode itself...

# The MOS diode

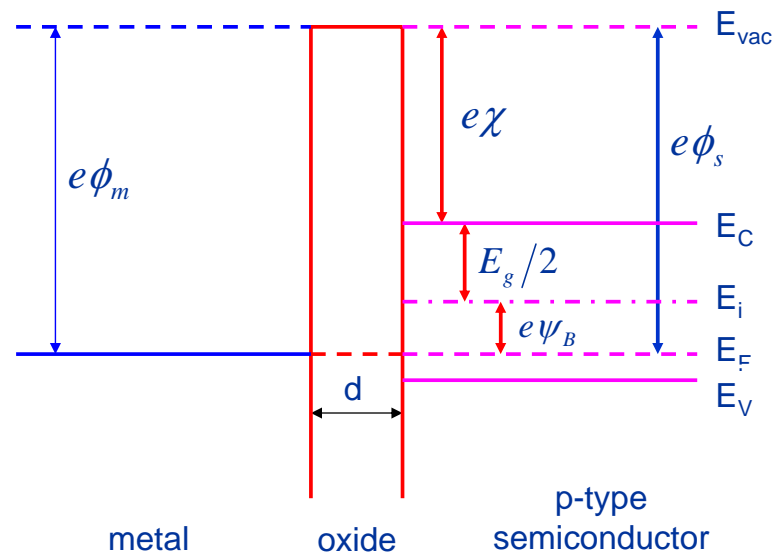


The metal-oxide-semiconductor (MOS) diode has the following structure as you would expect,



$V$  is the voltage applied to the metal contact and is positive if the applied bias is positive with respect to the Ohmic contact.

# Band diagram



At thermal equilibrium, with no bias applied the Fermi levels of the metal and semiconductor are aligned

# Ideal MOS diode



An ideal MOS diode is defined as follows,

1) At zero applied bias, the energy difference between the metal and the semiconductor work functions is zero (the flat-band condition),

$$e\phi_{ms} = e\phi_m - e\phi_s = e\phi_m - \left( e\chi + \frac{E_g}{2} + e\psi_B \right) = 0$$

2) The only charges which exist in the system at any bias are those in the semiconductor and those with equal and opposite sign on the metal surface.

3) There is no carrier transport through the oxide under dc-biasing conditions.

For the purposes of our discussion we will consider a p-type semiconductor MOS diode.

# MOS diode under bias accumulation

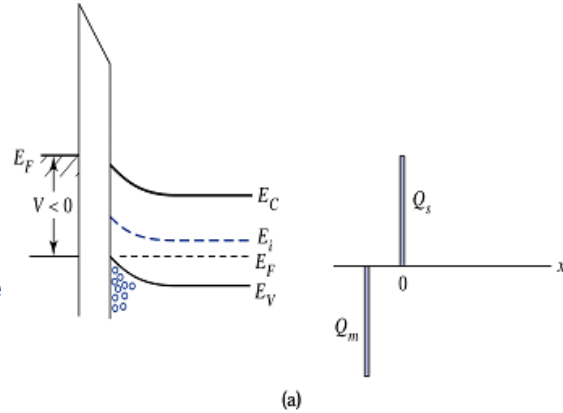


## Negative bias ( $V < 0$ )

No current flows so semiconductor Fermi level constant. The bands bend upwards. Excess holes are induced at the semiconductor-oxide interface.

$$p_p = n_i e^{(E_i - E_F)/kT}$$

Since  $E_i - E_F$  is increased at the semiconductor surface, holes accumulate near the interface. This is known as the *accumulation case*.



$$|Q_m| = Q_s$$

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# MOS diode under bias depletion



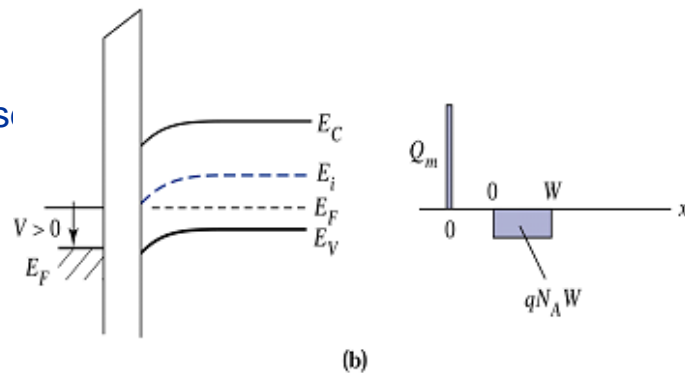
## Small positive bias ( $V > 0$ )

When a small positive bias is applied to the MOS diode, the bands bend downward, and the majority carriers are depleted.

$$p_p = n_i e^{(E_i - E_F)/kT}$$

This is known as the *depletion case*.

$$Q_{sc} = -eN_A W$$



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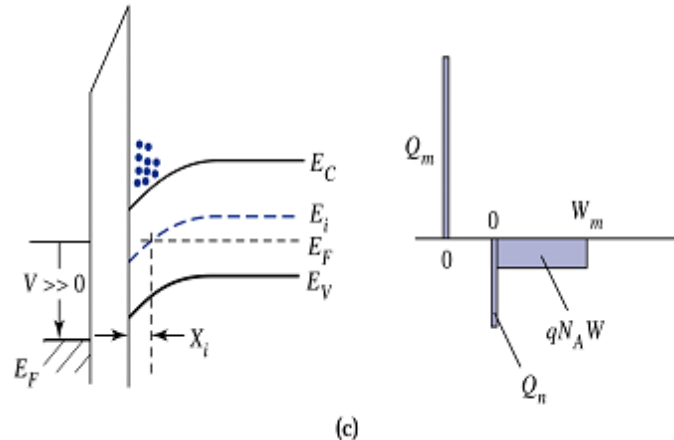
## MOS diode under bias inversion

### Large positive bias ( $V > 0$ )

When a large positive bias is applied to the MOS diode, the energy bands bend downward, even more so that the intrinsic Fermi level at the surface crosses the Fermi level.

$$n_p = n_i e^{(E_F - E_i)/kT}$$

This is known as the *inversion* case. Where the minority carrier concentration (electrons) at the surface exceeds the majority carrier concentration (holes).



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## MOS diode under bias

### strong inversion

*Weak inversion* begins as soon as  $(E_F - E_i) > 0$ , and the minority carrier concentration increases exponentially.

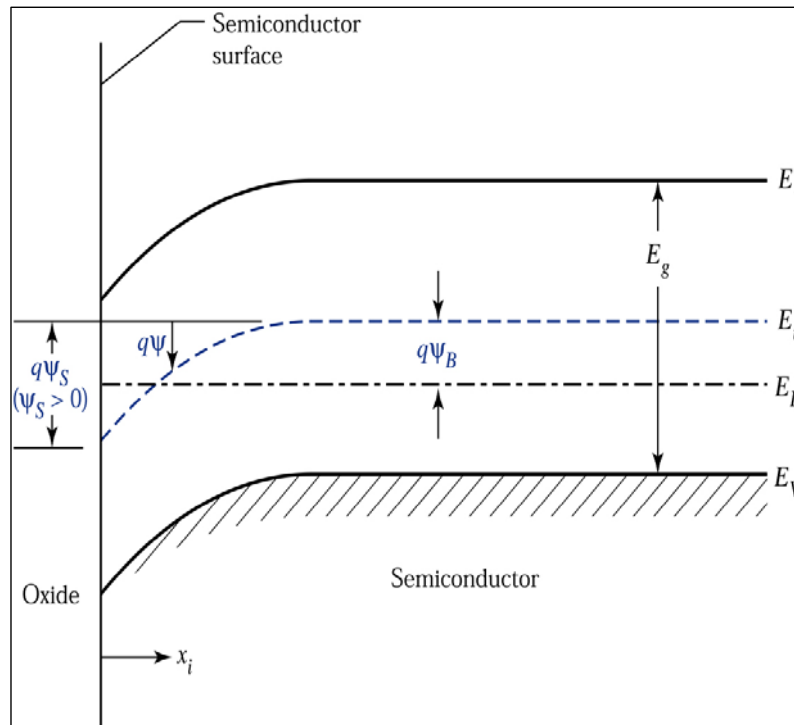
*Strong inversion* occurs when the minority carrier concentration is equal to the substrate doping level, (although convenient, this is a largely arbitrary criterion).

Beyond this point most of the additional negative charges consist of the charge  $Q_n$  in a very narrow *n*-type inversion layer of width  $x_i$  at the oxide-semiconductor interface ( $x_i \sim 1-10 \text{ nm} \ll W$ ).

The depletion width is at its maximum ( $W_m$ ) at strong inversion since a small increase in band bending results in a very large increase in  $Q_n$ .

$$Q_s = Q_n + Q_{sc} = Q_n - eN_A W_m$$

# Surface depletion region



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# Electrostatic potential

Band-bending is described in terms of a quantity which we will call the electrostatic potential. This is defined as zero in the bulk and is a measure of the intrinsic Fermi level position with respect to the bulk intrinsic Fermi level.

At the semiconductor surface,

$$\psi = \psi_s \quad \text{Surface potential}$$

Since the electron and hole concentrations are given by,

$$n_p = n_i e^{(E_F - E_i)/kT} \quad \& \quad p_p = n_i e^{(E_i - E_F)/kT}$$

We can express them too as a function of the electrostatic potential,

$$n_p = n_i e^{q(\psi - \psi_B)/kT} \quad \& \quad p_p = n_i e^{q(\psi_B - \psi)/kT}$$

Positive when bands bent downwards

$E_i - E_F$

# Accumulation to Inversion



The carrier concentrations at the surface are therefore,

$$n_s = n_i e^{q(\psi_s - \psi_B)/kT} \quad \& \quad p_s = n_i e^{q(\psi_B - \psi_s)/kT}$$

The following regions of surface potential are therefore identified,

$\psi_s < 0$  Accumulation of holes (bands bent upward)

$\psi_s = 0$  Flat-band condition

$0 < \psi_s < \psi_B$  Depletion of holes (bands bent downward)

$\psi_s = \psi_B$  Intrinsic condition ( $n_s = n_p = n_i$ )

$\psi_s > \psi_B$  Inversion (bands bent downward)

# Depletion width



We can think of the surface depletion region as a one sided  $n^+ - p$  abrupt junction where the built-in potential is replaced by the surface potential,

$$W = \sqrt{\frac{2\epsilon_s \psi_s}{eN_A}}$$

Our earlier convenient-but-arbitrary definition stated that at the onset of strong inversion the electron concentration at the surface is equal to the substrate impurity concentration ( $n_s = N_A$ ),

$$n_i e^{e(\psi_s(inv) - \psi_B)/kT} = n_i e^{e\psi_B/kT}$$

$$\psi_s(inv) \cong 2\psi_B = \frac{2kT}{e} \ln\left(\frac{N_A}{n_i}\right) \quad \text{Band diagram}$$

# Depletion width



When the surface is strongly inverted the depletion width is at its maximum,

$$W_m = \sqrt{\frac{2\epsilon_s \psi_s(\text{inv})}{eN_A}} \cong \sqrt{\frac{2\epsilon_s 2\psi_B}{eN_A}}$$

$$W_m = \sqrt{\frac{4\epsilon_s kT \ln(N_A/n_i)}{e^2 N_A}}$$

# C-V Characteristics



In the absence of any work function differences, the applied bias will appear partly across the oxide and partly across the semiconductor,

$$V = V_o + \psi_s$$

The potential across the oxide is given

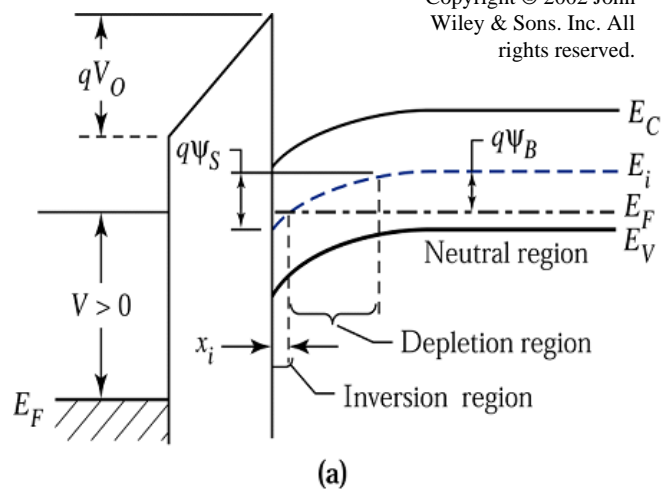
by, 
$$V_o = F_o d$$

$$V_{ox} = \frac{|Q_s|d}{\epsilon_{ox}}$$

$$C_{ox} = \epsilon_{ox} / d$$

$$V_{ox} = \frac{|Q_s|}{C_{ox}}$$

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# C-V Characteristics

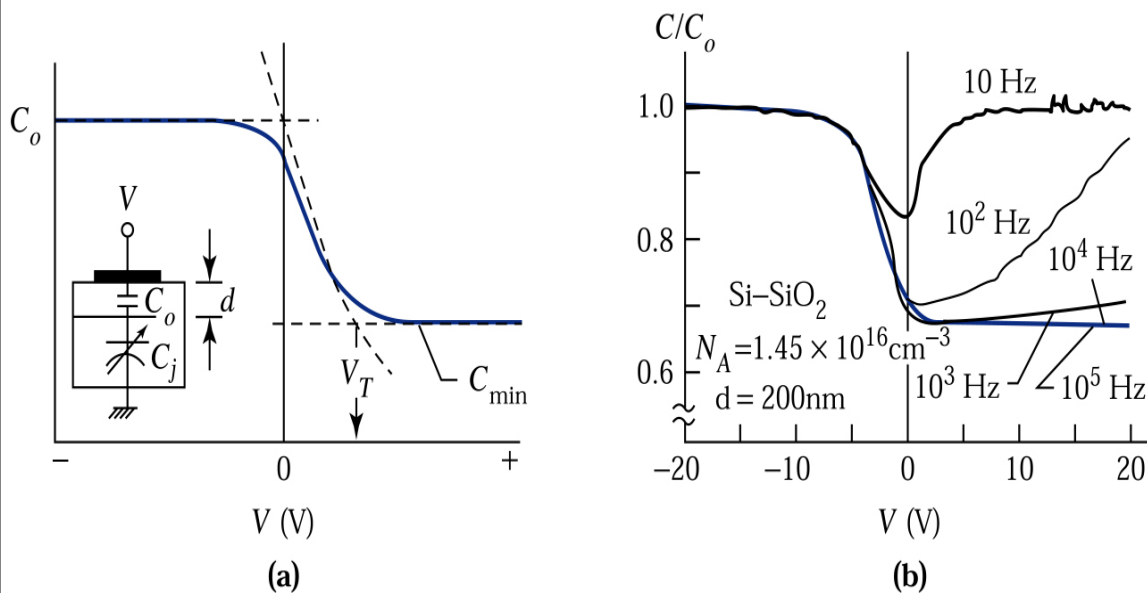
The total capacitance of the MOS diode is a series combination of the oxide capacitance and the semiconductor depletion-layer capacitance,

$$C = \frac{C_o C_j}{(C_o + C_j)} \quad \text{where,} \quad C_j = \frac{\epsilon_s}{W}$$

$$C_o = \frac{\epsilon_{ox}}{d}$$

When the applied bias is negative, there is no depletion layer and we have accumulation of holes at the surface of the semiconductor. In this case, the total capacitance is close to that of the oxide.

# C-V Characteristics



**Figure 6.7.** (a) High-frequency MOS C-V curve showing its approximated segments (dashed lines). Inset shows the series connection of the capacitors. (b) Effect of frequency on the C-V curve.<sup>2</sup>



# Threshold voltage



When the semiconductor surface is strongly inverted, the width of the depletion region is at its maximum. This occurs at a plate voltage that causes the surface potential to reach its inversion value. This is known as the threshold voltage,

$$V = V_o + \psi_s$$
$$V_T = V_o + \psi_s(\text{inv})$$

$$V_T = \frac{eN_A W_m}{C_o} + \psi_s(\text{inv}) \cong \frac{\sqrt{2\epsilon_s eN_A (2\psi_B)}}{C_o} + \psi_B$$

Beyond strong inversion, the capacitance will remain at a minimum value,

$$C_{\min} = \frac{\epsilon_{ox}}{d + (\epsilon_{ox}/\epsilon_s)W_m} \quad \text{since,} \quad C_j = \frac{\epsilon_s}{W_m}$$

# Real Si-SiO<sub>2</sub> MOS diodes



The work function difference between the metal and the semiconductor is generally not zero as in our idealised case, and certainly isn't for the most commonly used metals in the metal-Si-SiO<sub>2</sub> system...

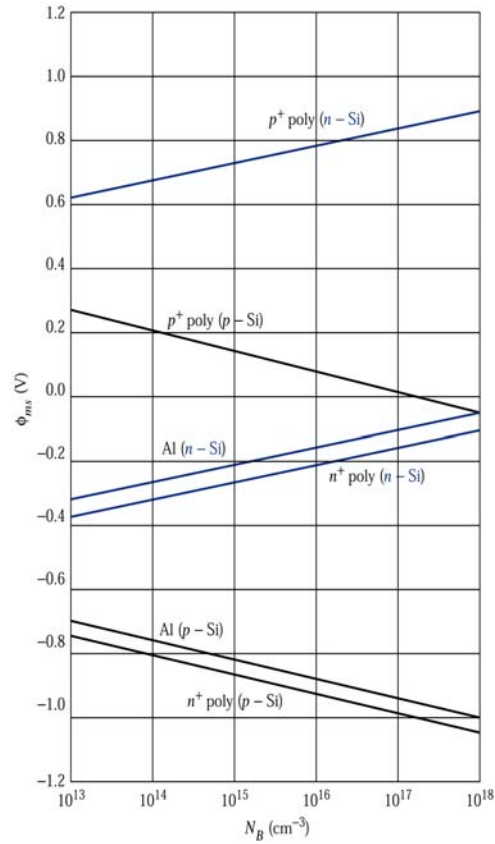
$$\phi_m = 3.95eV \quad \text{n}^+\text{-polysilicon}$$

$$\phi_m = 4.1eV \quad \text{Aluminium}$$

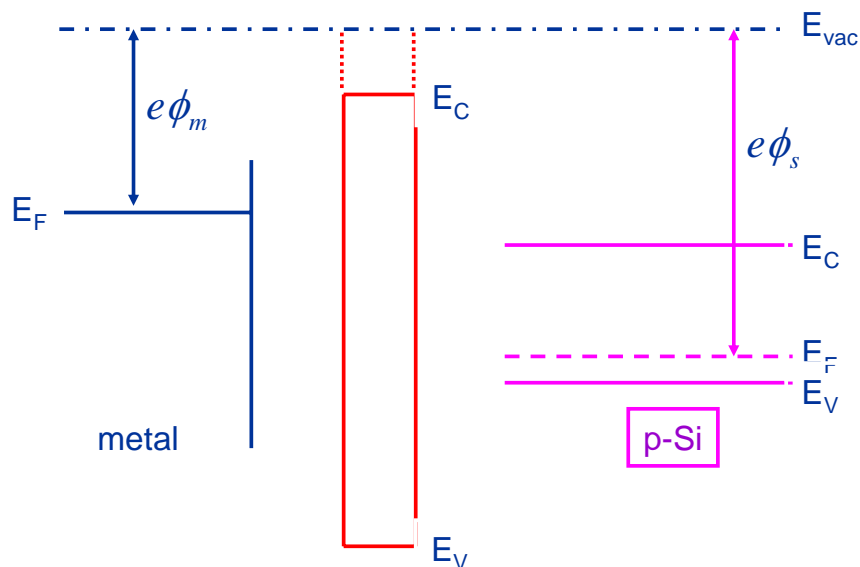
$$e(\phi_m - \phi_s) < 0 \quad \text{For all doping levels of Si}$$

How will this affect our band diagram?

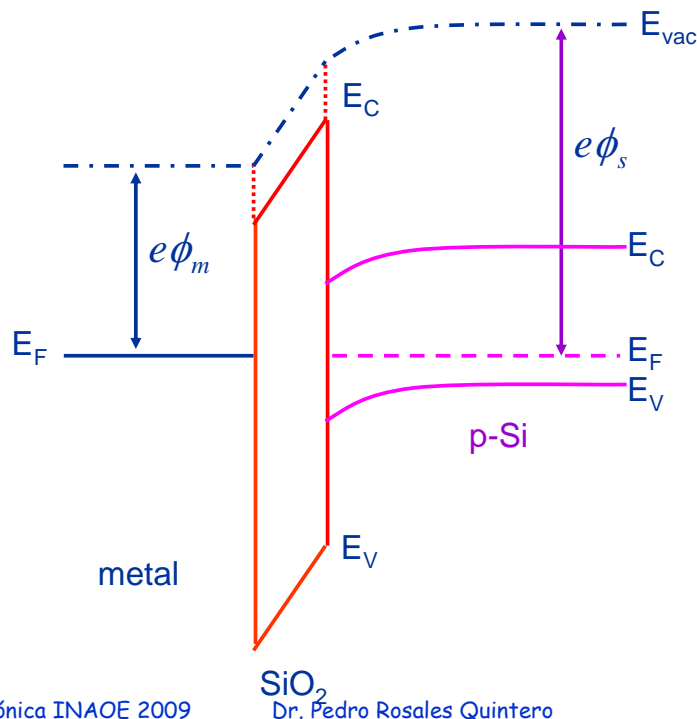
**Figure 6.8.**  
Work function difference as a function of background impurity concentration for Al,  $n+$ , and  $p+$  polysilicon gate materials.



## Si-SiO<sub>2</sub> band diagram



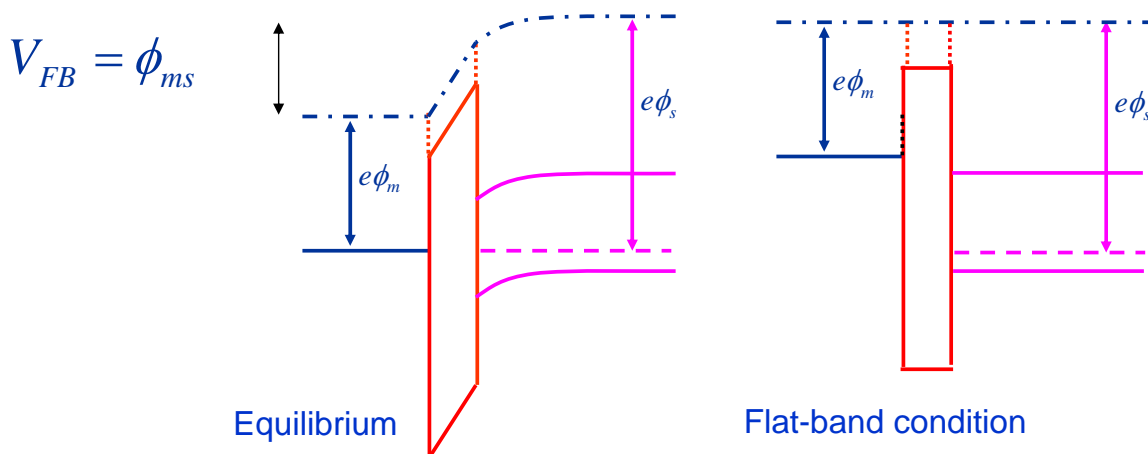
# Si-SiO<sub>2</sub> band diagram



# Flat-band voltage

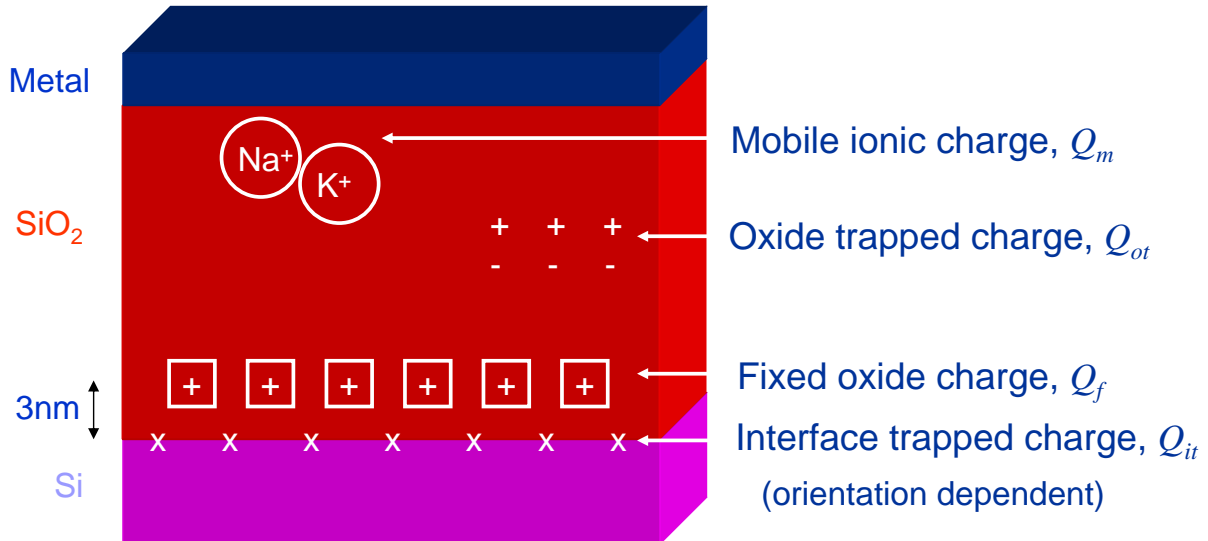
At thermal equilibrium, the bands are bent downwards so the semiconductor surface is negatively charged, and the metal positively charged.

In order to get back to the flat-band condition discussed for our ideal MOS diode we need to apply a negative bias to the metal (the flat-band voltage),

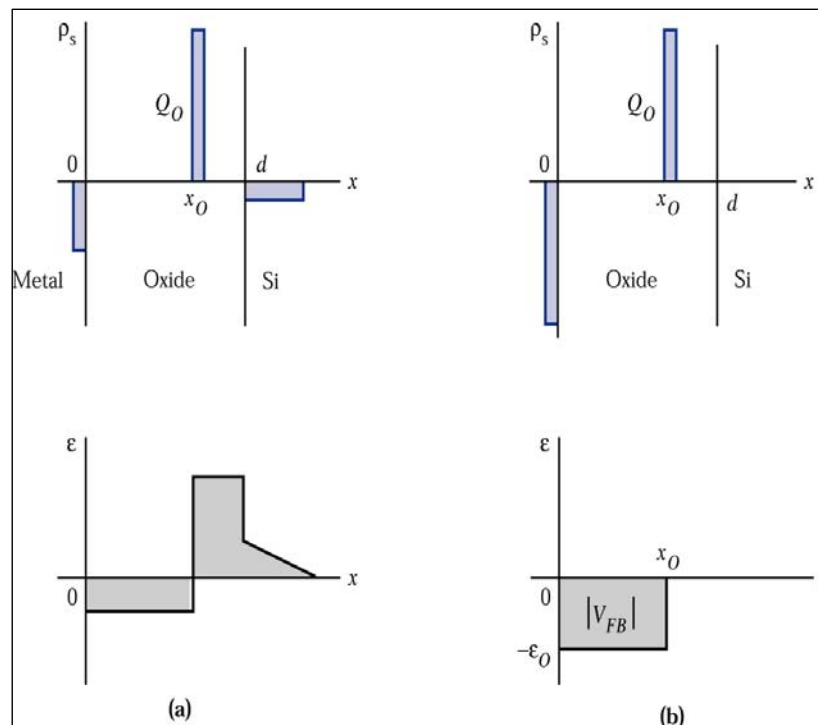


# Traps & charges

Real MOS diodes are also affected by charges trapped within the oxide and the interface...



# Oxide charges & the flat-band voltage



# Oxide charges & the flat-band voltage



Consider a positive charge sheet per unit area,  $Q_o$  within the oxide, inducing negative charges on both the metal and the semiconductor.

The flat-band condition is reached by increasing the charges on the metal (by applying a negative voltage,  $V_{FB}$ ) to reduce the electric field distribution at the semiconductor surface to zero.

The area under the electric field profile at this point gives the flat-band voltage,

$$V_{FB} = -F_o x_o = -\frac{Q_o}{\epsilon_{ox}} x_o = -\frac{Q_o}{C_o} \frac{x_o}{d}$$

# Oxide charges & the flat-band voltage

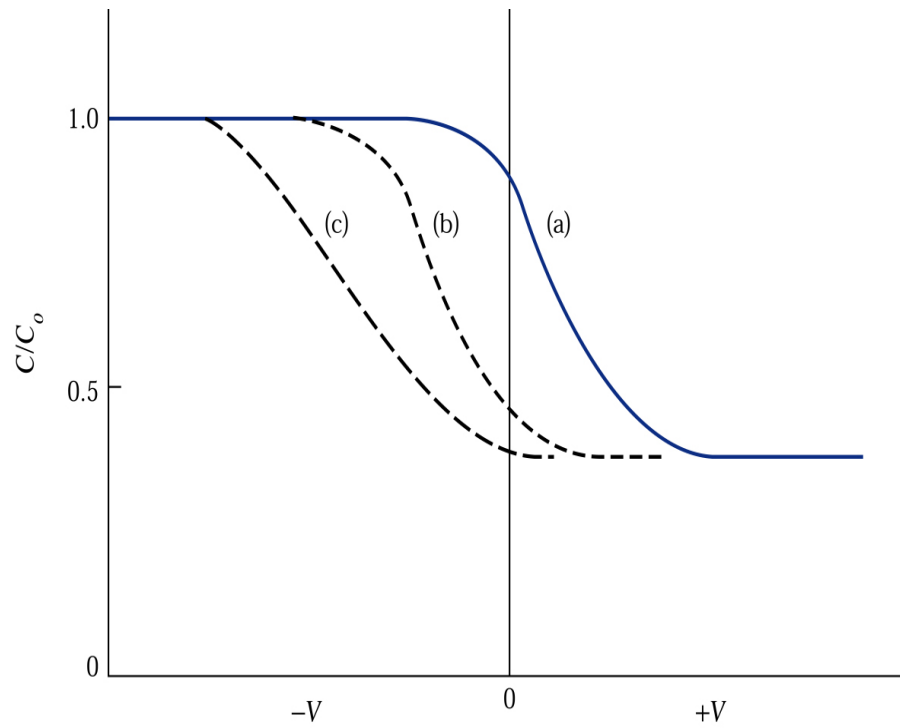


For an arbitrary space charge distribution within the oxide we can integrate the volume charge density,

$$V_{FB} = -\frac{1}{C_o} \left[ \frac{1}{d} \int_0^d x \rho(x) dx \right]$$

For a real diode in which the work function difference is nonzero and the interface-trapped charge is negligible, the flat-band voltage is given by,

$$V_{FB} = \phi_{ms} - \frac{(Q_f + Q_m + Q_{ot})}{C_o}$$



**Figure 6.12.** Effect of a fixed oxide charge and interface traps on the C-V characteristics of an MOS diode.